

Lesker U

Vacuum Technology Series



University of Utah Utah Nanofab

Workshop Topics Include:

Introduction to Vacuum Technology Including:

Adsorption, Desorption, Diffusion and Permeation
Gas-Solid Interactions
Flow Regimes
Conductance
Vacuum Pump Technologies, Pumping Speed and
Pump Throughput
Detecting leaks in vacuum systems

Physical Vapor Deposition and Thin Film Growth Models Including:

Thermal & E-beam evaporation
Sputtering by Direct Current (DC) & Rf
Cathodic Arc Deposition
Thin Film Growth Models
The Structure Zone model(s)
Stress in thin films
Deposition rate and film characteristics

Course Schedule with approximate times

Monday, September 19th, 2016

- Introduction to Vacuum Technology 9:00 a.m. to 12:00pm.
- Physical Vapor Deposition and Thin Film Growth Models: 12:30pm – 4:00pm
- Lunch will be provided to registered attendees (please email amy.van@utah.edu to register)

Location: SMBB Auditorium, Room 2650, University of Utah Campus

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